

09695715_CLSTITLES

Titles of Most Frequently Occurring Classifications of Patents Returned

From A Search of 09695715 on October 25, 2001

3	438/692	(0 OR, 3 XR)
	Class 438 :	SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS
	438/689	CHEMICAL ETCHING
	438/690	.Combined with the removal of material by nonchemical means (e.g., ablating, abrading, etc.)
	438/691	..Combined mechanical and chemical material removal
	438/692	...Simultaneous (e.g., chemical-mechanical polishing, etc.)
2	330/285	(0 OR, 2 XR)
	Class 330 :	AMPLIFIERS
	330/250	WITH SEMICONDUCTOR AMPLIFYING DEVICE (E.G., TRANSISTOR)
	330/278	.Including gain control means
	330/285	..Having particular biasing means
2	340/7.58	(0 OR, 2 XR)
	Class 340 :	COMMUNICATIONS: ELECTRICAL
	340/825	SELECTIVE
	340/825.36	.Having indication or alarm (e.g., location indication)
	340/7.2	..Code responsive (i.e., paging)
	340/7.58	...Alert
2	342/128	(0 OR, 2 XR)
	Class 342 :	COMMUNICATIONS: DIRECTIVE RADIO WAVE SYSTEMS AND DEVICES
	342/118	DETERMINING DISTANCE
	342/128	.With frequency modulation
2	342/175	(1 OR, 1 XR)
	Class 342 :	COMMUNICATIONS: DIRECTIVE RADIO WAVE SYSTEMS AND DEVICES
	342/175	WITH PARTICULAR CIRCUIT
2	342/70	(1 OR, 1 XR)
	Class 342 :	COMMUNICATIONS: DIRECTIVE RADIO WAVE SYSTEMS AND DEVICES
	342/61	RETURN SIGNAL CONTROLS EXTERNAL DEVICE
	342/70	.Radar mounted on and controls land vehicle

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2 348/554 (2 OR, 0 XR)
 Class 348 : TELEVISION
 348/553 BASIC RECEIVER WITH ADDITIONAL FUNCTION
 348/554 .Multimode (e.g., composite, Y, C; baseband RF

)

2 375/261 (1 OR, 1 XR)
 Class 375 : PULSE OR DIGITAL COMMUNICATIONS
 375/259 SYSTEMS USING ALTERNATING OR PULSATING CURRENT

 375/260 .Plural channels for transmission of a single
 pulse train
 375/261 ..Quadrature amplitude modulation

2 438/424 (2 OR, 0 XR)
 Class 438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS

 438/400 FORMATION OF ELECTRICALLY ISOLATED LATERAL
 SEMICONDUCTIVE STRUCTURE
 438/424 .Grooved and refilled with deposited dielectri
 c
 material

2 438/427 (0 OR, 2 XR)
 Class 438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS

 438/400 FORMATION OF ELECTRICALLY ISOLATED LATERAL
 SEMICONDUCTIVE STRUCTURE
 438/424 .Grooved and refilled with deposited dielectri
 c
 material
 438/427 ..Refilling multiple grooves of different
 widths or depths

2 438/435 (0 OR, 2 XR)
 Class 438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS

 438/400 FORMATION OF ELECTRICALLY ISOLATED LATERAL
 SEMICONDUCTIVE STRUCTURE
 438/424 .Grooved and refilled with deposited dielectri
 c
 material
 438/435 ..Multiple insulative layers in groove

2 438/443 (0 OR, 2 XR)
 Class 438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS

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438/400 FORMATION OF ELECTRICALLY ISOLATED LATERAL
SEMICONDUCTIVE STRUCTURE
438/439 .Recessed oxide by localized oxidation (i.e.,
LOCOS)
438/443 ..Etchback of recessed oxide

2 438/700 (0 OR, 2 XR)
Class 438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS

438/689 CHEMICAL ETCHING
438/694 .Combined with coating step
438/700 ..Formation of groove or trench

2 438/701 (0 OR, 2 XR)
Class 438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS

438/689 CHEMICAL ETCHING
438/694 .Combined with coating step
438/700 ..Formation of groove or trench
438/701 ...Tapered configuration

2 438/702 (0 OR, 2 XR)
Class 438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS

438/689 CHEMICAL ETCHING
438/694 .Combined with coating step
438/700 ..Formation of groove or trench
438/702 ...Plural coating steps

2 438/792 (0 OR, 2 XR)
Class 438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS

438/758 COATING OF SUBSTRATE CONTAINING SEMICONDUCTOR
REGION OR OF SEMICONDUCTOR SUBSTRATE
438/778 .Insulative material deposited upon
semiconductive substrate
438/791 ..Silicon nitride formation
438/792 ...Utilizing electromagnetic or wave energy
(e.g., photo-induced deposition, plasma, et

c.)

2 438/793 (0 OR, 2 XR)
Class 438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS

438/758 COATING OF SUBSTRATE CONTAINING SEMICONDUCTOR
REGION OR OF SEMICONDUCTOR SUBSTRATE
438/778 .Insulative material deposited upon

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		semiconductive substrate
438/791	..Silicon nitride formation	
438/792	...Utilizing electromagnetic or wave energy	
	(e.g., photo-induced deposition, plasma, e	
tc.)		
438/793Organic reactant	
2	438/794	(0 OR, 2 XR)
	Class	438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS
	438/758	COATING OF SUBSTRATE CONTAINING SEMICONDUCTOR
		REGION OR OF SEMICONDUCTOR SUBSTRATE
	438/778	.Insulative material deposited upon
		semiconductive substrate
	438/791	..Silicon nitride formation
	438/794	...Organic reactant

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Most Frequently Occurring Classifications of Patents Returned
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Original Classifications

2 348/554
2 438/424

Cross-Reference Classifications

3 438/692
2 330/285
2 340/7.58
2 342/128
2 438/427
2 438/435
2 438/443
2 438/700
2 438/701
2 438/702
2 438/792
2 438/793
2 438/794

Combined Classifications

3 438/692
2 330/285
2 340/7.58
2 342/128
2 342/175
2 342/70
2 348/554
2 375/261
2 438/424
2 438/427
2 438/435
2 438/443
2 438/700
2 438/701
2 438/702
2 438/792
2 438/793
2 438/794

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PLUS Search Results for S/N 09695715, Searched October 25, 2001

5881376
4573215
6240142
5455680
4607376
6173011
6229866
6069956
5956095
6175279
5495255
5614909
5510847
5479378
5585860
6018305
6066968
6137949
6137537
6175740
6084474
6208581
5537676
5019736
5222043
5640534
5914885
6131044
6037759
5418498
5485100
5485223
5692055
5694386
5771191
6121834
6169808
6175270
5517254
5834675
6057781
6144243
4817146
5770970
5903192
4529963

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5990523
6171976
6221734
6221734